

<b>FORM PTO-1449</b> (REV. 6-89)		U.S. DEPARTMENT OF COMMERCE Patent and Trademark Office		Attorney's Docket No. <b>3154</b>	Serial No. <b>08/984,558</b>	
<b>INFORMATION DISCLOSURE CITATION</b>				Applicants <b>David Alumot, et al.</b>		
(Use several sheets if necessary)				Filing Date <b>12/03/97</b>	Group Art Unit <b>2721</b> <b>Unassigned</b>	
<b>U.S. PATENT DOCUMENTS</b>						
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AAJ	5 6 9 9 4 4 7	12/16/97	Alumot, et al.	382	145	<b>RECEIVED</b> <b>FEB 09 1999</b> <b>GROUP 2700</b>
AAJ	4 7 4 0 7 0 8	04/26/88	Batchelder	250	563	
AAJ	** 4 5 8 9 1 4 0	05/86	Bishop, et al.	382	8	
AAJ	** 5 1 3 3 6 0 1	07/92	Cohen, et al.	356	Group	
AAJ	** 4 9 2 6 4 8 9	05/90	Danielson, et al.	382	8	
AAJ	4 4 4 1 1 2 4	04/03/84	Heebner, et al.	358	106	
AAJ	4 2 8 6 2 9 3	08/25/81	Jablonowski	358	199	
AAJ	5 1 5 3 6 6 8	10/06/92	Katzir, et al.	356	237	
AAJ	** 4 6 9 3 6 0 8	09/87	Kitagawa, et al.	356	394	
AAJ	** 5 1 5 9 6 4 6	10/92	Kumagai	382	34	
AAJ	** 5 2 0 4 9 1 0	04/93	Lebeau	382	8	
<b>FOREIGN PATENT DOCUMENTS</b>						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes No
<b>OTHER DOCUMENTS</b> (Including Author, Title, Date, Pertinent Pages, Etc.)						
AAJ		S. Kimura., K. Suda, S. Hase and C. Munakata, "Optical Method for Inspecting LSI Patterns Using Reflected Diffraction Waves", Vol. 27, No. 6, p. 1187-1192, March 15, 1986.				
AAJ		J.S. Batchelder, "Pattern Wafer Scanner", IBM Technical Disclosure Bulletin, Vol. 27, No. 10B, p. 6273-6275, March, 1985.				
AAJ		J.S. Batchelder, "Review of Contamination Detection on Patterned Surfaces", SPIE, Vol. 774, Lasers in Microlithography, p. 8-12, 1987.				
AAJ		P.S. Grosewald, J.E. Levine. and A.C. Rapa, "Automatic Detection of Defects on Wafers", IBM Technical Disclosure Bulletin, Vol. 21, No. 6, p. 2336-2337, November, 1978.				
AAJ		J.G. de la Rosa and D.M. Rose, "Wafer Inspection with a Laser Scanning Microscope", AT&T Technical Journal, p. 68-77.				
EXAMINER	ANDREW W. JOHNS PRIMARY EXAMINER			DATE CONSIDERED <b>MAR 24 1999</b>		
EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered.						
Include copy of this form with next communication to applicant. **, No copy enclosed. Reference was cited in parent application 07/790,871.						

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U.S. PATENT DOCUMENTS									
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate			
ANT	** 4 8 7 2 0 5 2	10/89	Liudzius, et al.	358	106				
ANT	** 4 7 9 1 5 8 6	12/88	Maeda, et al.	364	491				
ANT	** 4 7 6 4 9 6 9	08/88	Ohtombe, et al.	382	8				
ANT	5 0 5 8 1 7 8	10/15/91	Ray	382					
ANT	** 4 6 1 8 9 3 8	10/86	Sandland, et al.	364	552				
ANT	** 4 8 0 5 1 2 3	02/89	Specht, et al.	364	559				
ANT	4 7 3 1 8 5 5	03/15/88	Suda, et al.	382	8				
ANT	4 8 4 5 5 5 8	07/04/89	Tsai, et al.	358	106				
ANT	4 6 8 1 4 4 2	07/21/87	Wagner	356	237				
ANT	** 4 5 3 2 6 5 0	07/85	Wihl, et al.	382	8				

  

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	

  

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)			

  

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